## Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1-100. (Canceled)

101. (Currently Amended) A method of manufacturing an electro-luminescent device, the method-comprising the steps of: comprising:

forming pixel electrodes on above a substrate;

forming a solid insulating layer on above the pixel electrodes;

enhancing a liquid repellency of an upper surface of the solid insulating layer, while the solid insulating layer is in a solid state;

patterning the solid insulating layer so as to expose a part of each of the pixel electrodes and an inner wall of the solid insulating layer after enhancing the liquid repellency at the upper surface of the solid insulating layer, the upper surface of the solid insulating layer having a greater liquid repellency than a liquid repellency of the inner wall of the solid insulating layer; and

applying one of an optical material and a liquid precursor on the part of the pixel electrodes.

- 102. (Previously Presented) A method of manufacturing an electro-luminescent device according to claim 101, wherein enhancing the liquid repellency at the upper surface of the solid insulating layer is performed by one of an ultraviolet ray irradiation and an irradiation of plasma.
- 103. (Currently Amended) A method of manufacturing an electro-luminescent device, the method-comprising the steps of: comprising:

forming pixel electrodes on above a substrate;

forming an insulating layer on above the pixel electrodes;

patterning the insulating layer so as to expose a part of each of the pixel electrodes and an inner wall of the insulating layer;

enhancing a liquid repellency of an upper surface of the insulating layer after patterning the insulating layer so that the upper surface of the insulating layer has a greater liquid repellency than a liquid repellency of the inner wall of the insulating layer; and applying one of an optical material and a liquid precursor on the part of the pixel electrodes.

- 104. (Previously Presented) A method of manufacturing an electro-luminescent device according to claim 103, wherein enhancing the liquid repellency at the upper surface of the insulating layer is performed by one of an ultraviolet ray irradiation and an irradiation of plasma.
- 105. (Currently Amended) A method of manufacturing an active matrix type electro-luminescent device having a plurality of first electrodes, a second electrode and a plurality of organic semiconductor films, each of the plurality of the organic semiconductor films being disposed between one of the plurality of the first electrodes and the second electrode, the method emprising the steps of:comprising:

forming the plurality of the first electrodes at predetermined positions on above a substrate, the first electrodes being electrically coupled to corresponding ones of a plurality of transistors;

forming an insulating layer so as to surround the predetermined positions; positions where the first electrodes are formed;

arranging a liquid solution including an organic semiconductor material and a solvent, at each of the predetermined positions where the first electrodes are formed above of the substrate respectively; substrate:

evaporating the solvent so as to form the organic semiconductor films; and

forming the second electrode above the organic semiconductor films,

enhancing an affinity to liquid of the first electrodes at the predetermined positions where the first electrodes are formed relative to an affinity to liquid of the insulating layer, the affinity to liquid being enhanced with respect to the liquid solution.

- 106. (Canceled)
- 107. (Previously Presented) The method of manufacturing an active matrix type electro-luminescent device according to claim 105, wherein the insulating layer covers at least a part of each of the first electrodes.
- 108. (Currently Amended) The method of manufacturing an active matrix type electro-luminescent device according to claim 105, further comprising:

forming an interlayer film on above the insulating layer, the interlayer film being repellent to the liquid solution compared to the first electrodes.

- 109. (Previously Presented) The method of manufacturing an active matrix type electro-luminescent device according to claim 105, wherein arranging the liquid solution at the predetermined positions of the substrate is performed by an ink jet method.
- 110. (Currently Amended) A method of manufacturing an active matrix type electro-luminescent device having a plurality of first electrodes, a second electrode and a plurality of organic semiconductor films, each of the plurality of the organic semiconductor films being disposed between one of the plurality of the first electrodes and the second electrode, the method emprising the steps of comprising:

forming the plurality of the first electrodes at predetermined positions on above the surface of a substrate respectively, substrate, the first electrodes being electrically coupled to corresponding ones of a plurality of transistors;

forming an insulating layer so as to surround the predetermined positions;

enhancing an affinity to liquid of the first electrodes relative to an affinity to liquid of the insulating layer, the affinity to liquid being enhanced with respect to a liquid solution that includes an organic semiconductor material and a solvent;

arranging the liquid solution on above each of the plurality of the first electrodes respectively;

evaporating the solvent so as to form the organic semiconductor films; and forming the second electrode above the organic semiconductor films.

- 111. (Previously Presented) The method of manufacturing an active matrix type electro-luminescent device according to claim 110, wherein the insulating layer is repellent to the liquid solution, compared to the first electrodes.
- 112. (Previously Presented) The method of manufacturing an active matrix type electro-luminescent device according to claim 110, wherein a side-wall of the insulating layer is less repellent to the liquid solution, compared to a top of the insulating layer.
  - 113-122. (Canceled)
- 123. (Currently Amended) A method of manufacturing an active matrix type electro-luminescent device, the method-comprising the steps of: comprising:

forming a plurality of first electrodes, the first electrodes being electrically coupled to corresponding ones of a plurality of transistors;

forming an insulating layer so as to surround the pixel electrodes; and arranging an optical material at the pixel electrodes, a first liquid repellency of an inner wall of the insulating layer to a liquid or a liquid material being lower than a second liquid repellency of an upper surface of the insulating layer.

124. (Previously Presented) A method of manufacturing an electro-luminescent device according to claim 101, further comprising forming a second electrode over the solid insulating layer and the one of the optical material and the liquid precursor.

- 125. (Previously Presented) A method of manufacturing an electro-luminescent device according to claim 103, further comprising forming a second electrode over the insulating layer and the one of the optical material and the liquid precursor.
- 126. (Previously Presented) A method of manufacturing an active matrix type electro-luminescent device according to claim 105, the step of forming the second electrode includes forming the second electrode above the insulating layer.
- 127. (Previously Presented) A method of manufacturing an active matrix type electro-luminescent device according to claim 110, the step of forming the second electrode includes forming the second electrode above the insulating layer.
- 128. (Previously Presented) A method of manufacturing an active matrix type electro-luminescent device according to claim 123, further comprising forming a second electrode over the insulating layer and the optical material.
- 129. (Previously Presented) A method of manufacturing an electro-luminescent device according to claim 102, wherein enhancing a liquid repellency at the surface of the solid insulating layer is performed by an irradiation of a plasma including fluorine.
- 130. (Previously Presented) A method of manufacturing an electro-luminescent device according to claim 104, wherein enhancing a liquid repellency at the surface of the insulating layer is performed by an irradiation of a plasma including fluorine.